Serial No. Not Yet Assigned AP9 Rec'd PCT/PTO 01 SEP 2006
Atty. Doc. No. 2003P16079WOUS

ABSTRACT

Cracks are conventionally difficult to clean which often leads to damage to other regions of the component for cleaning. According to the invention, a plasma cleaning method is used, whereby a pressure and/or a separation of an electrode to the component are varied, in order to achieve a plasma cleaning in the crack.